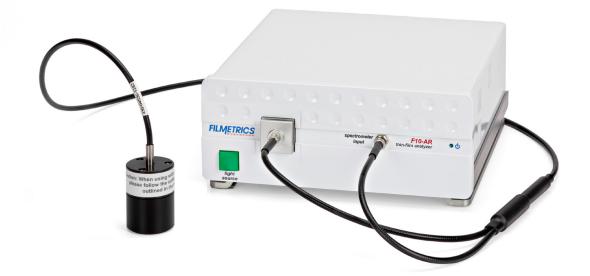
# **F10-AR** Thin-Film Analyzer



## Anti-Reflection and Hardcoat Testing at a New Level of Simplicity and Affordability

Automated testing of ophthalmic coatings is quick and easy with the Filmetrics F10-AR. Now everyone from line operators to R&D personnel can test and record coating performance in seconds.

### **Compare Multiple Spectra**

Plot and compare multiple reflectance spectra to target spectra – automatically evaluating reflectance levels, minima/ maxima locations, and generating unambiguous good/bad readings.

### **Quantify Residual Color**

Residual color can be displayed visually as well as in all of the common color space systems, such as CIELAB and CIEXYZ.

# Use the Hardcoat Upgrade to Measure Thickness

The optional Filmetrics FFT algorithm is used in hundreds of hardcoat applications worldwide. Measure hardcoat and primer layers simultaneously, all with a single click.

### All with Unprecedented Simplicity

Adjustments common to other spectrometers, such as integration time and baselining, have been virtually eliminated due to proprietary Filmetrics advances. This means that you concentrate on your lenses, not the equipment.



#### The Filmetrics Advantage

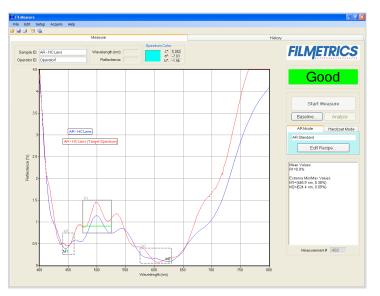
- World's leader in tabletop thin-film measurement
- 24-hour phone, e-mail, and online support
  Intuitive analysis software standard with every system

### **Additional Features**

- Built-in online diagnostics
- Standalone analysis software included
- Sophisticated history function for saving, reproducing, and plotting results







The F10-AR makes automatic quantitative assessment of lens coatings quick and easy.

	F10-AR	F10-AR-EXR	F10-AR-NIR	F10-AR-UV	F10-AR-UVX
Thickness Measurement Range*:	0.2 µm-15 µm	0.2 μm-30 μm	0.5 µm-30 µm	0.1 µm-15 µm	0.1 µm-30 µm
Min. Thickness to Measure n & k*:	100 nm	100 nm	500 nm	50 nm	50 nm
Accuracy*: The greater of	0.01 µm or 0.2%	0.01µm or 0.2%	% 0.02 μm or 0.4%	0.01 µm or 0.2%	0.01 µm or 0.2%
Precision <sup>1</sup> :	0.001 µm	0.001 µm	0.002 µm	0.001 µm	0.001 µm
Stability <sup>2</sup> :	0.001 µm	0.001 µm	0.002 µm	0.001 µm	0.001 µm
Spot Size:	100 µm				
Sample Size:	From 1 mm to 300 mm diameter and up				
Light Source Lamp MTBF:	Internal, Halogen			External D2 + Halogen	
Spectrometer					
Wavelength Range:	380-1050 nm	380-1700 nm	950-1700 nm	190-1100 nm	190-1700 nm
Wavelength Accuracy:	< 0.5 nm				
Wavelength Reproducibility	0.1 nm				
Photometric Accuracy:	0.01 A				
Noise:	< 0.0002 A rms				
Stray Light	< 0.25% at 500 nm		<0.5% at 1400 nm	< 0.25% at 500 nm	
General			aterial dependent		
Power Requirements: 1	00-240 VAC, 50-60		<sup>1</sup> 1σ of 100 measurements of 500 nm SiO <sub>2</sub> -on-Si. Average of 1σ over 20 successive days. <sup>2</sup> 2σ of daily average of 100 measurements of 500 nm SiO <sub>2</sub> -on-Si over 20 successive days.		
Certifications: C	E EMC and safety	directives <sup>2</sup> 20			
Operating System	suc	successive days.			

PC:	Windows XP (SP2) - Latest Windows (64-bit)
Mac:	OS X Lion - Latest Mac OS running Parallels



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